

FORM PTO-1449
(REV. 7-80)U.S. DEPARTMENT OF COMMERCE
PATENT AND TRADEMARK OFFICE

ATTY. DOCKET NO.

SERIAL NO.

TI-36749

LIST OF DOCUMENTS CITED BY APPLICANT

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APPLICANT

Christopher L. Kelley

FILING DATE

GROUP

December 10, 2003

U.S. PATENT DOCUMENTS

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		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUB- CLASS	TRANSLATION Yes No
	BA						
	BB						
	BC						
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OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

5F	CA	"Applied Centura DPS Etch - DPS Plus for Metal Applications", website http://www.appliedmaterials.com/products/metal_etch_dps_plus_centura.html , printed on 12/4/2003, 1 page.
	CB	"Applied Centura DPS Etch - DPS II for Metal Applications", website http://www.appliedmaterials.com/products/metal_etch_dps_ii_centura_300.html , printed on 12/4/2003, 1 page.
	CC	"Applied Centura DPS Etch - DPS Plus for Silicon Applications", website http://www.appliedmaterials.com/products/silicon_etch_dps_plus.html , printed on 12/4/2003, 1 page.
	CD	"Applied Centura DPS Etch - DPS II for Silicon Applications", website http://www.appliedmaterials.com/products/silicon_etch_dps_ii_300.html , printed on 12/4/2003, 1 page.
	CE	"Applied Centura eMAX Etch", website http://www.appliedmaterials.com/products/dielectric_etch_emax.html , printed on 12/4/2003, 1 page.

EXAMINER

DATE CONSIDERED

1-10-06

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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JF	CA	"Applied Centura Enabler Etch", website http://www.appliedmaterials.com/products/dielectric_etch_enabler.html , printed on 12/4/2003, 1 page.
↓	CB	"Applied Centura EnTek Etch - for Dielectric Applications", website http://www.appliedmaterials.com/products/dielectric_etch_emax_entek.html , printed on 12/4/2003, 1 page.
↓	CC	"Applied Producer Etch", website http://www.appliedmaterials.com/products/producer_etch.html , printed on 12/04/2003, 1 page.
↓	CD	"Applied Centura HART Etch for Silicon Applications", website http://www.appliedmaterials.com/products/silicon_etch_hart.html , printed on 12/4/2003, 1 page.
↓	CE	

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